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CHANGE OF CORRESPONDENCE ADDRESS**

I, *Dr. Graham Fisher, Director of Intellectual Property of MEMC Electronic Materials, Inc.*, the Assignee of the entire right, title, and interest in the *U.S. Patent Application(s) and/or Patent(s) identified on the attached Schedule A*, hereby revoke all previous powers of attorney or authorizations of agent given and do hereby appoint the attorneys or agents associated with the following Customer Number, with full power of substitution and revocation, to prosecute and transact all business in the Patent and Trademark Office connected therewith for the *U.S. Patent Application(s) and/or Patent(s) listed in the attached Schedule A*:

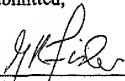
Customer Number: 76681

Please direct all correspondence in connection with said *U.S. Patent Application(s) and/or Patent(s)* to:

Customer Number: 76681

Respectfully submitted,

Date: 5/13/2008


Dr. Graham Fisher
Director of Intellectual Property
MEMC Electronic Materials, Inc.

PATENT

THE UNITED STATES PATENT AND TRADEMARK OFFICE

STATEMENT UNDER 37 CFR 3.73(b)

MEMC Electronic Materials, Inc., a Delaware Corporation, pursuant to 37 CFR 3.73(b), hereby states that it is the Assignee of the entire right, title, and interest in *U.S. Patent Application(s) and/or Patent(s) on the attached Schedule A*.

The entire rights, title, and interest in the aforementioned Patent Application(s) and/or Patent(s) were conveyed to *MEMC Electronic Materials, Inc.* via Assignment(s) recorded with the United States Patent and Trademark Office at the *Reel/Frame Numbers on the attached Schedule A*.

The undersigned, *Dr. Graham Fisher, Director of Intellectual Property*, has full authorization to act on behalf of Assignee *MEMC Electronic Materials, Inc.*

Respectfully submitted,

Date: 5/13/2008



Dr. Graham Fisher
Director of Intellectual Property
MEMC Electronic Materials, Inc.

APPENDIX A
Owned by MEMC Electronic Materials, Inc.

ATTORNEY REFERENCE	CONF. NO	PUBLICATION NO. & DATE	SERIAL NO. & FILING DATE	PATENT NO. & ISSUE DATE	CURRENT OWNER/ASSIGNEE	REEL AND FRAME NO.	TITLE
MEMC2554.1	6190	US-2002-0083889-A1 7/4/2002	10/073,506 2/11/2002	6,743,289 6/11/2004	MEMC Electronic Materials, Inc.	Division of 09/04/16 986 recorded at 01/08/18/0677	THERMAL ANNEALING PROCESS FOR PRODUCING LOW DEFECT DENSITY SINGLE CRYSTAL SILICON
MEMC2581	5850	US-2002-0134-302-A1 9/26/2002	09/615,506 3/23/2001	6,579,352 6/17/2003	MEMC Electronic Materials, Inc.	0-189-70/263	HEAT SHIELD ASSEMBLY FOR CRYSTAL PULLER
MEMC2583	9825		09/649,304 8/30/2003	6,456,474 6/20/2002	MEMC Electronic Materials, Inc.	0-10936/274	NON CONTAMINATING GAS/TIGHT VALVE FOR SEMI CONDUCTOR APPLICATIONS
MEMC2607	6082		09/505,289 2/16/2000	6,479,386 1/1/2002	MEMC Electronic Materials, Inc.	0-10830/104	PROCESS FOR REDUCING SURFACE VARIATIONS FOR POLISHED WATER
MEMC2614	6202	US-2002-00837719-A1 12/4/2002	09/415,320 12/31/1999	6,638,357 6/26/2003	MEMC Electronic Materials, Inc.	0-10862/062	METHOD FOR REVEALING AGGLOMERATED INTRINSIC POINT DEFECTS IN SEMICONDUCTOR CRYSTALS
MEMC2632	5009		09/502,340 2/16/2000	6,776,840 8/17/2004	MEMC Electronic Materials, Inc.	0-10851/0457	METHOD OF CONTROLLING DIAMETER OF A SILICON CRYSTAL IN A LOCKED SEED LIFT GROWTH PROCESS
MEMC2633	5899		10/449,481 1/21/2000	6,135,823 1/13/2001	MEMC Electronic Materials, Inc.	0-10152-747 recorded at 00981/21/56	CONTINUOUS OXIDATION PROCESS FOR CRYSTAL PULLING APPARATUS
MEMC2840.1	9314	US-2003-008421-A1 19/2/2003	09/659,207 11/2/2001	6,495,922 1/26/2002	MEMC Electronic Materials, Inc.	0-1262/70/04	PROCESS FOR MAKING WAFERS FOR ION IMPLANTATION MONITORING
MEMC2841	4942		09/566,830 5/8/2000	6,444,027 9/3/2002	MEMC Electronic Materials, Inc.	0-11035/18	MODIFIED SUSCEPTOR FOR USE IN CHEMICAL VAPOR DEPOSITION PROCESS
MEMC2841.4	9780	US-2003-0041789-A1 36/2/2003	09/729,415 6/18/2002	6,652,850 1/25/2003	MEMC Electronic Materials, Inc.	0-10566-830 recorded at 01/10/05/0186	MODIFIED SUSCEPTOR FOR USE IN CHEMICAL VAPOR DEPOSITION PROCESS
MEMC2842	6444		09/723,847 1/12/2000	6,515,752 2/4/2003	MEMC Electronic Materials, Inc.	0-11320/0946	DEFECT CLASSIFICATION USING SCATTERED LIGHT INTENSITIES
MEMC2843	4580	US-2003-0037761-A1 1/8/2001	09/752,222 1/22/2000	5,596,095 7/22/2003	MEMC Electronic Materials, Inc.	0-11620/0217	AN EPITAXIAL SILICON WAFER FREE FROM AUTO DOING AND BACKSIDE HAZARD AND A METHOD AND APPARATUS FOR THE PREPARATION THEREOF
MEMC2844	4222		09/653,981 9/6/2000	6,454,635 5/24/2002	MEMC Electronic Materials, Inc.	0-11246/0312	METHOD AND APPARATUS FOR A WATER CARRIER HAVING AN INSERT
MEMC2851	6310		09/503,586 2/14/2000	6,344,093 2/5/2002	MEMC Electronic Materials, Inc.	0-10783/0603	PROCESS FOR PRODUCING A SILICON MELT
MEMC2841.4	2620	US-2002-0020338-A1 2/2/2002	09/643,600 8/30/2001	6,585,645 1/25/2003	MEMC Electronic Materials, Inc.	0-10503-586 recorded at 01/07/03/053	CONTINUATION OF 09/643,600 recorded at 01/07/03/053
MEMC2841.5	5192	US-2002-0038874-A1 7/4/2002	10/036,875 6/15/2004	6,749,863 6/15/2004	MEMC Electronic Materials, Inc.	0-1722/0302	PROCESS FOR PRODUCING A SILICON MELT
MEMC2859	1982		09/621,525 3/8/2000	6,350,312 2/26/2002	MEMC Electronic Materials, Inc.	0-10830/146 and 0-12139/0404	STRONTIUM DOPING OF MOLTEN SILICON FOR USE IN CRYSTAL GROWING PROCESS